

SUPERCritical CPD MEMS DRYER FOR 4" WAFERS **AUTOSAMDRI[®]-815B, SERIES C**

UNPARALLELED VERSATILITY AND LOW LCO₂ CONSUMPTION



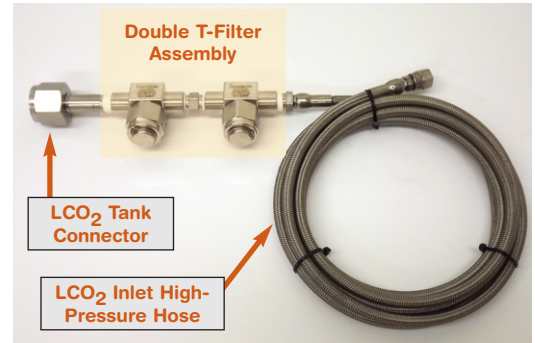
tousimis

- The **Autosamdri[®]-815B, Series C** maintains tousimis[®] process quality and achieves a small facility foot print while utilizing an efficient closed loop refrigeration and waste alcohol collection design.*
- 35 years of tousimis[®] CPD experience enables smooth operation and precise control. HF Compatible Wafer Holders* and Chamber Inserts* are provided allowing anti-stiction MEMS processing of various wafer sizes and die.

- 40% Less LCO₂ Consumption.¹
- Process up to 5 wafers in Less than 1 hour.
- All inclusive Small Foot Print design.
- Minimal installation Site Preparation required.
- On Site Start-Up and User Training included.²

FEATURES

- High efficiency internal closed loop refrigeration.* (22°C to operational in less than 4 minutes)!
- Post-Purge-Filter easily accessible for maintenance ease.*
- The patented internal SOTER™ condenser* quietly captures and separates CO₂ exhaust and waste alcohols.
- Unique chamber inserts* enable variance of chamber I.D. maximizing efficiency in LCO₂ consumption, process time, and providing multiple size wafer process capability!
- Process up to 5 x 6" wafers per process run. Also comes with additional HF Compatible Wafer Holders* to process 5 x 4", 5 x 3", 5 x 2" diameter wafers or 5 x 10mm square die (tousimis® HF compatible Wafer Holders* may be used to etch and process your wafers minimizing handling).
- Chamber illumination with viewing window facilitates chamber status visualization.*
- Microprocessor controller allows for complete automatic processing.*
- All internal surfaces are inert to CO₂ and ultrapure alcohols.
- Repeatable operating parameters insuring "reproducibility" of results.
- Static pressure control module helps insure automatic safe pressure stability.
- Internal filtration system delivers clean LCO₂ into process chamber down to 0.08µm.
- Control panel LED's instantly indicate process mode at a glance.
- Clean room static-free compatible design.
- All electronic components meet CE, UL and/or U.S. Military Specifications.



Standard Accessories



Standard Accessories

SPECIFICATIONS

- Cabinet: 19.8" (50.3cm) Width x 31.7" (80.6cm) Depth x 44.5" (113.0cm) Height
- System Set-Up Area Footprint: 27" (68.6cm) Width x 38" (96.5cm) Depth
- Chamber size: 6.50" I.D. x 1.25" Depth / Chamber volume: 679 ml
- Temperature gauge range: -30°C to 60°C, Pressure gauge range: 0 to 2,000 psi
- 120V / 50-60Hz (Other voltage units also available. Please Inquire)
- LCO₂ flow is controlled through Micro Metering Valves with Vernier handles for easily control flow rates.*

STANDARD ACCESSORIES

- LCO₂ High Pressure braided stainless steel inert Teflon® lined hose. 10ft (~ 3m) long for clean room operation (Other lengths available upon request at a nominal charge).
- Double T-Filter Assembly (#8785) pre-installed onto the chamber LCO₂ supply high-pressure hose. Flows LCO₂ twice thru 0.5 µm filters with 99.5% particulate retention prior to LCO₂ entering Automegasamdri®-915B.
- Tool set included for connecting LCO₂ chamber supply line.
- Static free exhaust tubing for all exhaust outlets.
- Internal stainless and nickel scintered filtration systems incorporated to protect lines, wafers, and valves down to 0.4µm.
- Spare chamber O-ring (3), chamber lamps (2), and slo-blow fuses.
- Complete wafer size process flexibility! 4 chamber inserts* enable 6.5" chamber ID reduction down to smaller chamber ID sizes for processing wafers and die from a range including: 6", 4", 3", 2", and 1.25" ! Allows for multiple wafer size drying.
- 6", 4", 3", 2" diameter wafer holders and 10mm square die holders included. Holders are HF compatible and can holds up to 5 wafers or die each.
- 2 year warranty on all parts and labor. Free lifetime technical support consultation by our scientific staff.

¹ Compared with tousimis Automegasamdri®-915B, Series B

² Available for most countries. Contact tousimis for details.

* Most Automegasamdri® feature U.S. patents (# 6,493,964, #6,678,968) or patents pending.

Note: Actual delivered model or accessories may vary slightly, as advancements are being constantly applied.